

**Notice of References Cited**

Application/Control No.

09/835,643

Applicant(s)/Patent Under

Reexamination

AHN ET AL.

Examiner

Leonardo Andújar

Art Unit

2826

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**U.S. PATENT DOCUMENTS**

* *	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-			
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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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